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ATTORNEY DOCKET NO. CONFIRMATION NO. FIRST NAMED INVENTOR FILING DATE APPLICATION NO. 15.55/6364 01/18/2002 Akihiko Ebina 10/050,793 **EXAMINER** 12/16/2003 24033 7590 DICKEY, THOMAS L KONRAD RAYNES VICTOR & MANN, LLP 315 SOUTH BEVERLY DRIVE PAPER NUMBER ART UNIT **SUITE 210** 2826 BEVERLY HILLS, CA 90212 DATE MAILED: 12/16/2003

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)
Office Action Summary		10/050,793	EBINA, AKIHIKO
		Examiner	Art Unit
		Thomas L Dickey	2826
The MAILING DATE of this communication appears on the cover sheet with the correspondence address			
Period fo	• -		
THE I - Exter after - If the - If NO - Failu - Any r	ORTENED STATUTORY PERIOD FOR REPL MAILING DATE OF THIS COMMUNICATION. sions of time may be available under the provisions of 37 CFR 1.7 SIX (6) MONTHS from the mailing date of this communication. period for reply specified above is less than thirty (30) days, a rep period for reply is specified above, the maximum statutory period re to reply within the set or extended period for reply will, by statute eply received by the Office later than three months after the mailined patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event, however, ma ly within the statutory minimum o will apply and will expire SIX (6) e, cause the application to becom	ly a reply be timely filed f thirty (30) days will be considered timely. MONTHS from the mailing date of this communication. le ABANDONED (35 U.S.C. § 133).
1)[🛛	Responsive to communication(s) filed on 17	October 2003 .	
2a)⊠	∑ This action is FINAL. 2b) This action is non-final.		
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.			
Disposition of Claims A) \(\sum_{\text{claim}} \) \(1.45 \) in/are pending in the application			
•	Claim(s) <u>1-15</u> is/are pending in the application		
4a) Of the above claim(s) is/are withdrawn from consideration. 5. ∇ Claim(s) 2.11 and 15 is/are allowed.			
5)⊠ Claim(s) <u>2-11 and 15</u> is/are allowed.			
6)⊠ Claim(s) <u>1 and 12-14</u> is/are rejected. 7)□ Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction and/or election requirement.			
•	ion Papers	or election requirement	
9) The specification is objected to by the Examiner.			
10)⊠ The drawing(s) filed on <u>25 September 2003</u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.			
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).			
11)☐ The proposed drawing correction filed on is: a)☐ approved b)☐ disapproved by the Examiner.			
If approved, corrected drawings are required in reply to this Office action.			
12)☐ The oath or declaration is objected to by the Examiner.			
Priority under 35 U.S.C. §§ 119 and 120			
13)⊠ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).			
a)	☑ All b)☐ Some * c)☐ None of:		
	1. Certified copies of the priority document	ts have been received.	
	2. Certified copies of the priority documen	ts have been received	in Application No
3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received.			
14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).			
a) \square The translation of the foreign language provisional application has been received. 15) \square Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.			
Attachmen			
2) 🔲 Notic	ce of References Cited (PTO-892) ce of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449) filed 10/17/03	5) Notic	view Summary (PTO-413) Paper No(s) e of Informal Patent Application (PTO-152) :

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DETAILED ACTION

1. The amendment filed on 09/25/03 has been entered.

Drawings

2. The proposed substitute sheets of drawings, filed on 09/25/03 have been approved.

Information Disclosure Statement

3. The Information Disclosure Statement filed on 10/17/03 has been considered.

Specification

- 4. The title of the invention is not descriptive. A new title is required that is clearly indicative of the invention to which the claims are directed. The following title is suggested: "NOVEL BiCMOS INVERTER." This title is suggested because every claim requires both bipolar and MOSFETS, of two different types (BiCMOS), arranged in an inverter circuit.
- **5.** Paragraph 001 is objected to for the following reason.

Applicants may refer to Japanese Application No. 2001-011859 as their priority document, but <u>incorporation by reference</u> of essential material in the specification to a foreign application or patent, or to a publication is improper. If indeed Japanese

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Application No. 2001-011859 contains essential material not covered by the present U.S. application. Applicant is required to amend the disclosure to include the material incorporated by reference. The amendment must be accompanied by an affidavit or declaration executed by the applicant, or a practitioner representing the applicant, stating that the amendatory material consists of the same material incorporated by reference in the referencing application. See In re Hawkins, 486 F.2d 569, 179 USPQ 157 (CCPA 1973); In re Hawkins, 486 F.2d 579, 179 USPQ 163 (CCPA 1973); and In re Hawkins, 486 F.2d 577, 179 USPQ 167 (CCPA 1973).

Claim Rejections - 35 USC § 103

- 6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1, 12,13, and 14 stand rejected under 35 U.S.C. 103(a) as being unpatentable over WOLF "Silicon Processing for the VLSI Era" in view of Manning (6,137,146) and SCHWANK et al. (6,268,630).

Wolf discloses a semiconducting device with a semiconductor layer, an element isolation region formed in the semiconductor layer; and a first element forming region and a second element forming region defined by the element isolation region; wherein the first element forming region includes both a first bi-polar transistor Q1 and a first

field effect transistor M1; the first bi-polar transistor Q1 includes a first emitter region of a first (n) conduction type, a first base region of a second (p) conduction type, and a first collector region of the first (n) conduction type, the first field effect transistor M1 includes a first gate electrode layer, a source region of the first (n) conduction type, and a drain region of the first (n) conduction type, the first field effect transistor M1 further includes a first body region of the second (p) conduction type formed at least between the source region of the first conduction type and the drain region of the first conduction type, the drain region of the first conduction type is electrically connected to the first collector region of the first conduction type, and the source region of the first conduction type is formed structurally isolated from the first emitter region of the first conduction type, and wherein the second element forming region includes both a second bi-polar transistor Q2 and a second field effect transistor M2, the second bi-polar transistor Q2 includes a second emitter region of the first (n) conduction type, a second base region of the second (p) conduction type, and a second collector region of the first (n) conduction type, the second field effect transistor M2 includes a second gate electrode layer, a source region of the second (p) conduction type, and a drain region of the second (p) conduction type, the second field effect transistor M2 further including a first body region of the first (n) conduction type formed at least between the source region of the second conduction type and the drain region of the second conduction type, the source region of the second conduction type is electrically connected to the second collector region of the first conduction type, the drain region of the second conduction type is electrically

connected to the second base region of the second conduction type, the first collector region of the first conduction type is electrically connected to the second emitter region of the first conduction type, and the first gate electrode layer is electrically connected to the second gate electrode layer. Note figures 7-74(a) (top figure. Note that this figure includes two extra MOSFETS that are not needed to meet the claim) and 7-75(a) of Wolf. Wolf does not disclose an insulation layer upon which the semiconductor layer is formed, or placing the first body region of the second conduction type in contact with and electrically connected to the first base region of the second conduction type, or electrically connecting the first body region of the second conduction type to the source region of the first conduction type, or electrically connecting the first body region of the first conduction type to the second collector region of the first conduction type. Wolf does, however, teach electrically connecting the source region of the first conduction type to the first base region of the second conduction type (as opposed to electrically connecting both of these regions to the first body region of the second conduction type), and naturally, as stated above as a claim limitation, Wolf teaches that the source region of the second conduction type is electrically connected to the second collector region of the first conduction type. With respect to claims 13 and 14, Wolf does not specifically disclose that the semiconductor layer is a silicon layer, nor does Wolf discuss reversing the conductivity types, making the first type p-type so that the type of the BPT bases. the second type, is n-type.

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However, Manning discloses a semiconductor device having an element forming region 18 which includes both a first bipolar transistor and a first field effect transistor. In common with the disclosure of Wolf, Manning shows the first bi-polar transistor includes a first emitter region 36 of a first conduction type, a first base region 26c of a second conduction type, and a first collector region 22 of the first conduction type and the first field effect transistor includes a first gate electrode layer 14f, a source region 40 of the first conduction type, and a drain region 36 (note that the region 36 forms both a drain region and an emitter region 36, just as does region A20 form both drain and emitter in applicant's illustration of an embodiment of the claimed invention) of the first conduction type, the first field effect transistor further includes a first body region 26 of the second conduction type formed at least between the source region 40 of the first conduction type and the drain region 36 of the first conduction type, the first body region 26 of the second conduction type is electrically connected to the source region 40 of the first conduction type, the drain region 36 of the first conduction type is electrically connected to the first collector region 22 of the first conduction type, and the source region 40 of the first conduction type is formed structurally isolated from the first emitter region 36 of the first conduction type. Furthermore, Manning shows the first body region (which is the part of 26c under the gate 14f) of the second conduction type is in contact with and thereby electrically connected to the first base region (the portion of part 26c formed between emitter 36 and collector 22) of the second conduction type, Note figure 9 and column 6 lines 1-32 of Manning.

Further, Schwank et al. discloses an SOI CMOS transistor including an insulation layer upon which the semiconductor layer is formed, wherein on the right side, the first body region 28 of the second conduction type is electrically connected to the source region 52 of the first conduction type by way of body tie 56 and electrode 58, and wherein on the left side, the first body region 28 of the first conduction type is electrically connected to the source region 52 of the second conduction type by way of the other body tie 56 and the other electrode 58. Note figure 1 of Schwank et al. Therefore, it would have been obvious to a person having skill in the art to augment Wolf's semiconducting device with the insulation layer upon which the semiconductor layer is formed such as taught by Schwank et al. in order to increase the transconductance to thus provide faster response and higher frequency operation, and to augment the semiconducting device by electrically connecting the first body region of the second conduction type to the source region of the first conduction type and thus to the first base region of the second conduction type, and electrically connecting the first body region of the first conduction type to the source region of the second conduction type. and thus to the second collector region of the first conduction type, such as taught by Schwank et al., in order to harden the device against SEU radiation. Also, it would have been obvious to a person having skill in the art to place the first body region of the second conduction type of Wolf's semiconducting device in contact with and electrically connected to the first base region of the second conduction type such as taught by

Manning, in order to save space on the surface of the semiconducting device to thus

increase the density of the logic circuitry.

combined, yield a device with two NPN bipolar transistors coupled to a PMOS and an NMOS transistor. This device has all the limitations of the semiconductor device of

With regard to claim 13, the teachings of Wolf, Manning, and Schwank et al.,

claim 13 except that in claim 13, with the first type defined as p type, the bipolar

transistors are PNP coupled to an NMOS and a PMOS transistor. Although the device

yielded by the teachings of Wolf, Manning, and Schwank et al. does not teach the exact

type of base, emitter, collector, source, drain, and body conductivities as that claimed by

Applicant, the conductivity type differences are considered obvious design choices and

are not patentable unless unobvious or unexpected results are obtained from these

changes. It appears that these changes produce no functional differences and therefore

would have been obvious. Note In re Leshin, 125 USPQ 416.

Allowable Subject Matter

7. Claim 15 is allowed over the references of record for the reasons set forth in paper

#7.

8. Claims 2-11 are allowed over the references of record for the following reasons:

A. As a starting point in the analysis of the allowability of claims 2-11, it is noted that

all of these claims require a device that includes an insulation layer; a semiconductor

layer formed on the insulation layer; an element isolation region formed in the

semiconductor layer; and a first element forming region and a second element forming region defined by the element isolation region; wherein the first element forming region includes both a first bi-polar transistor and a first field effect transistor; the first bi-polar transistor includes a first emitter region of a first conduction type, a first base region of a second conduction type, and a first collector region of the first conduction type, the first field effect transistor includes a first gate electrode layer, a source region of the first conduction type, and a drain region of the first conduction type, the first field effect transistor further includes a first body region of the second conduction type formed at least between the source region of the first conduction type and the drain region of the first conduction type, the first body region of the second conduction type is electrically connected to the source region of the first conduction type, the first body region of the second conduction type is electrically connected to the first base region of the second conduction type, the drain region of the first conduction type is electrically connected to the first collector region of the first conduction type, and the source region of the first conduction type is formed structurally isolated from the first emitter region of the first conduction type, and wherein the second element forming region includes both a second bi-polar transistor and a second field effect transistor, the second bi-polar transistor includes a second emitter region of the first conduction type, a second base region of the second conduction type, and a second collector region of the first conduction type, the second field effect transistor includes a second gate electrode layer, a source region of the second conduction type, and a drain region of the second

conduction type, the second field effect transistor further including a first body region of the first conduction type formed at least between the source region of the second conduction type and the drain region of the second conduction type, the first body region of the first conduction type is electrically connected to the second collector region of the first conduction type, the source region of the second conduction type is electrically connected to the second collector region of the first conduction type, the drain region of the second conduction type is electrically connected to the second base region of the second conduction type, the first collector region of the first conduction type is electrically connected to the second emitter region of the first conduction type, and the first gate electrode layer is electrically connected to the second gate electrode layer.

B. However, claims 2 and 3 each require the device described above in section 8A in combination with a first electrode layer that continues to a side section of the first gate electrode layer and reaches the element isolation region, wherein the first gate electrode layer is formed in a manner to cross over the element forming region, the source region of the first conduction type is formed in a first region surrounded by the first gate electrode layer in a forming region of the first field effect transistor, the first electrode layer, and the element isolation region, the drain region of the first conduction type and the collector region of the first conduction type are formed in a second region surrounded by the first gate electrode layer and the element isolation region, the emitter region of the first conduction type is formed in a third region surrounded by the first gate

electrode layer in a forming region of the first bi-polar transistor, the first electrode layer and the element isolation region, and the first body region of the second conduction type is formed at least below the first gate electrode layer in the forming region of the first field effect transistor, and below a part of the first electrode layer. Such a combination is neither disclosed nor suggested by the references of record.

C. Similarly, claims 4 and 5 each require the device described above in section 8A in combination with a first layer and a second layer, wherein the first layer has one end section continuing to the first gate electrode layer or the second layer, and another end section reaching the element isolation region, the second layer has one end section continuing to the first gate electrode layer or the second layer, and another end section reaching the element isolation region, the source region of the first conduction type is formed in a first region surrounded by the first gate electrode layer, the first layer and the element isolation region, the drain region of the first conduction type and the first collector region of the first conduction type are formed in a second region surrounded by the first gate electrode layer, the second layer and the element isolation region, the first emitter region of the first conduction type is formed in a third region surrounded by the first layer, the second layer and the element isolation region, the first base region of the second conduction type is formed below a part of the first layer, and below a part of the second layer in the semiconductor layer, and the first body region of the second conduction type is formed at least below the first gate electrode layer and below a part

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of the first layer in the semiconductor layer. Such a combination is neither disclosed nor suggested by the references of record.

D. Claim 6 requires the device described above in section 8A in combination with a second body region of the first conduction type, which is formed in the semiconductor layer between the first base region of the second conduction type and the first collector region of the first conduction type. Such a combination is neither disclosed nor suggested by the references of record.

E. Claims 7,8, and 10 each require the device described above in section 8A in combination with an impurity diffusion layer of the second conduction type formed in the first element forming region, wherein the impurity diffusion layer of the second conduction type is a semiconductor layer in the first region, and is formed in the semiconductor layer between the source region of the first conduction type and the first body region of the second conduction type, and the source region of the first conduction type and the first body region of the second conduction type are electrically connected to one another through the impurity diffusion layer of the second conduction type Such a combination is neither disclosed nor suggested by the references of record.

F. Claims 9 and 11 each require the device described above in section 8A in combination with a third body region of the second conduction type is formed in the semiconductor layer between the first collector region of the first conduction type and the first emitter region of the first conduction type and in the semiconductor layer

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adjacent to the element isolation region. Such a combination is neither disclosed nor suggested by the references of record.

Response to Arguments

9. Applicant's arguments filed 09/25/03 have been fully considered but they are not persuasive.

It is argued, at page 26 of the remarks, that "[Wolf teaches away from claim 1 because] the bipolar device of [Wolf's] Fig. 7-75(a)... appears to be isolated from the FET device by a trench." However, The Wolf reference is a work of scholarship. Wolf does not offer any particular advantages of the device he discloses, he simply reports that this device represents the state of the art as of the publication date of the Wolf reference.

It is further argued, at page 26 of the remarks, that "the emitter 36 and the source 36 are the same region 36 as shown in Figs. 7 and 8 of the Manning reference." However, this misrepresents the rejection. In the first place the rejection cites only figure 9 and not figures 7 or 8. In the second place, the rejection identifies part 40 (not part 36) as the source region of the first conduction type. Note section 6 above.

It is further argued, at page 26 of the remarks, that "claim 1 requires that 'the source region of the first conduction type is formed structurally isolated from the first emitter region of the first conduction type..." However, as the Examiner explains above, the source region 40 of the first conduction type is formed structurally isolated from the first

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emitter region 36 of the first conduction type, by virtue of being separated by a portion of the first body region 26c. Note section 6 above.

In response to applicant's argument that there is no suggestion to combine the references, the examiner recognizes that obviousness can only be established by combining or modifying the teachings of the prior art to produce the claimed invention where there is some teaching, suggestion, or motivation to do so found either in the references themselves or in the knowledge generally available to one of ordinary skill in the art. See In Re Fine 837 F.2d 1071, 5 USPQ 2d 1596 (CAFC 1988) and In re Jones, 958 F.2d 347, 21 USPQ 2d 1941 (CAFC 1992).

In this case, one of ordinary skill in the art would realize the advantages, in terms of cost and functionality, involved in reducing the size of an individual device and thus allowing more devices per chip. Applicant disclosed that eliminating a base-body contact layer would be advantageous (application, page 29, lines 13-16, as cited in the response) but applicant did not disclose that it would be advantageous in terms of reducing device size, increasing functionality, and reducing cost. The apparent reason applicant did not do so was that applicant realized that reducing device size, increasing functionality, and reducing cost, were goals anyone versed in the art would have taken for granted. It is not hindsight reasoning to ascribe to PHOSITA (the hypothetical person having ordinary skill in the art) motives that applicant, while writing his specification, took for granted PHOSITA would understand.

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Conclusion

10.THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, THIS ACTION IS MADE FINAL. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thomas L Dickey whose telephone number is 703-308-0980. After February 4, 2004, this telephone number will change to (571) 272-1913. The examiner can normally be reached on Monday through Thursday 8 AM to 6 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan Flynn can be reached on (703) 308-6601. The fax phone numbers

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for the organization where this application or proceeding is assigned are 703-872-9318 for regular communications and 703-872-9319 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-305-3900.

tld 12/2003

> doublinton Minhloan Tran Primary Examiner

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